UNITED STATES PATENT AND TRADEMARK OFFICE

BEFORE THE PATENT TRIAL AND APPEAL BOARD

Samsung Electronics Co., Ltd.,
Samsung Electronics America, Inc.,
Samsung Semiconductor, Inc., and
Samsung Austin Semiconductor, LLC.,
Petitioner

v.

Chien-Min Sung,
Patent Owner

Case IPR2024-00534
U.S. Patent No. 9,138,862

PETITIONER SAMSUNG'S
UPDATED TABLE OF EXHIBITS

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Patent Trial and Appeal Board
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P.O. Box 1450
Alexandria, VA 22313-1450

TABLE OF EXHIBITS

Petitioner Exhibit No.	DESCRIPTION
1001	U.S. Patent No. 9,138,862 ("'862 Patent")
1002	Declaration of Dr. Stanley Shanfield
1003	File History of the '862 Patent
1004	U.S. Patent Application Publication No. 2007/0060026 ("Sung'026")
1005	"The Organic Diamond Disk (ODD) for dressing of Polishing Pads of Chemical Mechanical Planarization," International Conference on Planarization / CMP Technology, 25-27 October 2007 ("SungICPT")
1006	U.S. Patent Application Publication No. 2008/0087644 ("Nishioka")
1007	International Patent Application Publication No. WO 2008/049019 ("Lin")
1008	U.S. Patent Application Publication No. 2009/0001581 ("Kim")
1009	U.S. Patent Application Publication No. 2009/0117692 ("Koyama")
1010	U.S. Patent No. 5,036,015
1011	Ishizuka et al. "PCD Dressers for Chemical Mechanical Planarization with Uniform Polishing" Proceedings of International Conference on Leading Edge Manufacturing in 21st Century: LEM21, 2007, Volume 2007.4
1012	U.S. Patent Application Publication No. 2008/0292869 (Sung'869)
1013	Fenna, Donald. "Hardness Numbers," *A Dictionary of Weights, Measures, and Units*, 1st ed., Oxford University Press, 2004.
1014	Tsai et al., "Effect of CMP conditioner diamond shape on pad topography and oxide wafer performances," *Int. J. Adv. Manuf. Technology*, 55: 253-262 (2011)
1015	Pysher et al. "Design, Characteristics and Performance of Diamond Pad Conditioners", Materials Research Society Symposium Procedures, Vol. 1249, 2010 ("Pysher")
1016	*Design, Characteristics and Performance of Diamond Pad Conditioners*. SpringerLink. https://link.springer.com/article/10.1557/PROC-1249-E02-04
1017	Exhibit 4 of Complaint in *Sung v. Samsung Electronics Co., Ltd. et al*, 4-23-cv-00752
1018	Scheduling Order in *Sung v. Samsung Electronics Co., Ltd. et al*, 4-

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	23-cv-00752
1019	Electronic Copy of SungICPT obtained from IEEE, the publisher
1020	Records for *Proceedings ICPT 2007* available at https://search.worldcat.org/title/198200505 from WorldCat; at https://d-nb.info/985874066 (bibliographic record and MARC21-XML record) from the online catalog of the German National Library; and from OCLC FirstSearch (subscription required for access)
1021	TIB records for *Proceedings ICPT 2007*, available at https://search.worldcat.org/title/552588043 from WorldCat; at https://opac.tib.eu/DB=1/LNG=EN/CLK?IKT=12&TRM=585918058 from the classic catalog of TIB; at https://www.tib.eu/en/search/id/TIBKAT:585918058/Proceedings-ICPT-International-Conference-on-Planarization?cHash=aa6c9dc952dc92d0d78d53ec988dc7a5from the TIB portal; and from OCLC FirstSearch (subscription required for access)
1022	Program and Invitation, ICPT International Conference on Planarization/CMP Technology, October 25 – 27, 2007, Hilton Hotel, Dresden, Germany, available at https://www.yumpu.com/en/document/read/19588721/program-and-invitation-eusar
1023	ICPT 2007 Conference Registration website, archived by Internet Archive on October 13, 2007, available at https://web.archive.org/web/20071013155043/http://icpt2007.com/Conferences_en/ICPT+2007/Conference+Registration/ from Internet Archive
1024	ICPT 2007 Program order form webpage, archive by Internet Archive on November 3, 2007, available at https://web.archive.org/web/20071103025949/http://icpt2007.com/Conferences_en/ICPT+2007/Conference+Program/Program+Order+Form.htm
1025	Online catalog of the German National Library archived on January 1, 2011 by Internet Archive, available at https://web.archive.org/web/20110101165839/www.d-nb.de/ from Internet Archive
1026	GetInfo Portal of the German National Library of Science and

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	Technology (TIB), archived on October 22, 2007 by the Internet Archive, available at https://web.archive.org/web/20071022114354/http://www.tib-hannover.de/en/getinfo-portal/ from Internet Archive
1027	Declaration of Dr. Ingrid Hsieh-Yee
1028	*Chien-Min Sung v. Samsung Electronics Co. Ltd., et al.*, Case No. 4:23-cv-00752 (E.D. Tex.), 82 (Order to Stay Pending Motion for Inter-District Transfer)
1029	*Chien-Min Sung v. Samsung Electronics Co. Ltd., et al.*, Case No. 4:23-cv-00752 (E.D. Tex.), 37 (February 14, 2024 Scheduling Order)
1030	*Chien-Min Sung v. Texas Instruments Inc.*, Case No. EDTX-4-23-cv-00753 (E.D. Tex.), 26 (TI's Motion for Summary Judgment of Invalidity)
1031	*Chien-Min Sung v. Texas Instruments Inc.*, Case No. EDTX-4-23-cv-00753 (E.D. Tex.), 68 (Order To Stay the Case Pending Resolution of TI's Motion for Summary Judgment).
1032	*Chien-Min Sung v. Samsung Electronics Co. Ltd., et al.*, Case No. 4:23-cv-00752 (E.D. Tex.), 56 (Motion to Stay Pending Resolution of Texas Instruments Incorporated's Motion for Summary Judgment)
1033	*Chien-Min Sung v. Samsung Electronics Co. Ltd., et al.*, Case No. 4:23-cv-00752 (E.D. Tex.), 72 (Plaintiff's Sur-reply)
1034	*Chien-Min Sung v. Samsung Electronics Co. Ltd., et al.*, Case No. 4:23-cv-00752 (E.D. Tex.), 43 (Notice Of Intent To File A Motion To Stay Pending Inter Partes Review)
1035	*Chien-Min Sung v. Samsung Electronics Co. Ltd., et al.*, Case No. 4:23-cv-00752 (E.D. Tex.), 56 (Motion To Stay Pending Resolution of TI MSJ)
1036	*Chien-Min Sung v. Samsung Electronics Co. Ltd., et al.*, Case No. 4:23-cv-00752 (E.D. Tex.), 62 (Plaintiff's Opposition to MTS Pending Resolution of TI MSJ)
1037	*Chien-Min Sung v. Samsung Electronics Co. Ltd., et al.*, Case No. 4:23-cv-00752 (E.D. Tex.), 67 (Defendant's Reply)
1038	*Chien-Min Sung v. Samsung Electronics Co. Ltd., et al.*, Case No. 4:23-cv-00752 (E.D. Tex.), 72 (Plaintiff's Sur-Reply)
1039	*In re: Chien-Min Sung Subpoena Upon 3M Company,* Case No.

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	0:2023mc00104 (D. Minnesota), 1 (3M's Nov. 16, 2023 Motion To Quash Subpoena In The District of Minnesota)
1040	*In re: Chien-Min Sung Subpoena Upon 3M Company,* Case No. 0:2023mc00104 (D. Minnesota), 15 (Dr. Sung's Nov. 22, 2023 Cross-Motion To Compel And Motion For Sanctions)
1041	*In re: Chien-Min Sung v. 3M Company*, Case No. 6:23-mc-00002 (N.D. Tex.), 1 (Dr. Sung's Nov. 27, 2023 Motion To Compel In The Northern District of Texas)
1042	*In re: Chien-Min Sung Subpoena Upon 3M Company,* Case No. 0:2023mc00104 (D. Minnesota), 38 (Court Entry Showing A Discovery Hearing Before The Court In The District Of Minnesota)
1043	Judge Jordan's Time To Order Motion of Summary Judgement Statistics
1044	Marked up M. Y. Tsai & Y. S. Liao (2009) Dressing Characteristics of Oriented Single Diamond on CMP Polyurethane Pad, Machining Science and Technology, 13:1, 92-105
1045	Marked up Tsai et al., "Effect of CMP conditioner diamond shape on pad topography and oxide wafer performances," Int. J. Adv. Manuf. Technology, 55: 253-262 (2011)
1046	Marked up M. Y. Tsai et al., Novel Diamond Conditioner Dressing Characteristics of CMP Polishing Pad, International Journal of Machine Tools & Manufacture 49 (2009) 722–729
1047	Deposition of Dr. Tsai in IPR2024-00533, Vol I
1048	Deposition of Dr. Tsai in IPR2024-00533, Vol II
1049	Deposition of Dr. Tsai in IPR2024-00534
1050	Single Diamond Dressing Characteristics of CMP Polyurethane Pad" *Key Engineering Materials* Vol 329 (2007) pp 151-156
1051	PCD Pad Conditioners for Low Pressure Chemical Mechanical Planarisation of Semiconductors" *Int. J. Abrasive Technology*, Vol. 1, Nos. 3/4, 2008
1052	"Dressing Behaviors of PCD Conditioners on CMP Polishing Pads" *Advanced Materials Research* Vols 76-78 (2009) pp 201-206
1053	"Mosaic Diamond Pad Conditioners for Improved CMP Performance" *ECS Transactions*, 27 (1) 575-580 (2010)
1054	"The Black Pad with Graphite Impregnation for CMP" *ECS Transactions*, 27 (1) 581-586 (2010)
1055	"The CMP by Polishing with GiP Dressed by BODD" *Advanced*

Petitioner Exhibit No.	DESCRIPTION
	Materials Research Vols 126-128 (2010) pp 1013-1018
1056	"Organic diamond disk versus brazed diamond disk for dressing a chemical–mechanical polishing pad" Diamond & Related Materials 23 (2012) 144–149
1057	"Development of a novel cooling system-assisted minimum quantity lubrication method for improvement of milling performance" *Journal of the Chinese Institute of Engineers*, 2015, Vol. 38, No. 3, 322–331
1058	U.S. Patent Application Publication No. 2010/0248595 ("Dinh-Ngoc")
1059	U.S. Application No. 11/223,786 ('786 Application)
1060-1069	*RESERVED*
1070	Petitioner's Demonstratives for Oral Argument

Dated: June 16, 2025

Respectfully submitted,

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CERTIFICATE OF SERVICE

Pursuant to 37 C.F.R. § 42.6(e), the undersigned certifies that on June 16, 2025, a complete copy of Petitioner's Updated Table of Exhibits and EX1070 - Petitioner's Demonstratives were served on counsel of record for the Patent Owner by filing the documents through P-TACTS and by sending via electronic mail to the following addresses:

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